



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 4508

Toshifumi KIMBA et al. : Docket No. 2000-1706A

Serial No. 09/734,737 : Group Art Unit 2877

Filed December 13, 2000 : Examiner Hoa Q. Pham

SUBSTRATE FILM THICKNESS :
MEASUREMENT METHOD, SUBSTRATE
FILM THICKNESS MEASUREMENT
APPARATUS AND SUBSTRATE
PROCESSING APPARATUS :
THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEE FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975.

AMENDMENT AFTER FINAL

RESPONSE UNDER 37. CFR 1.116
EXPEDITED PROCEDURE

EXAMINING GROUP 2877

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action of November 19, 2003, a Petition for a one month extension of time being filed concurrently herewith, please amend the above-identified application as follows.